



S O S G R O U P

LAM Research
490 AutoEtch Plasma Etch 150mm Configuration
SN 1694

LAM Research Autoetch 490 Plasma Etch

LAM 490 AutoEtcher

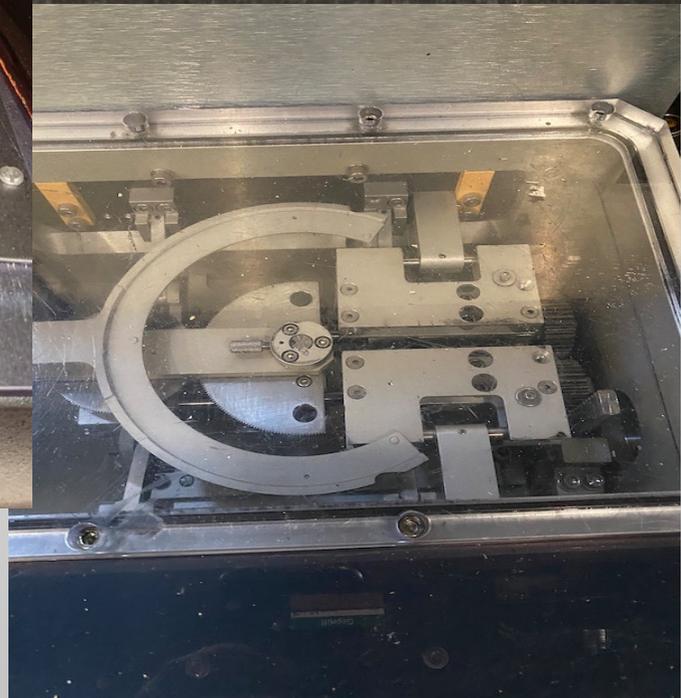
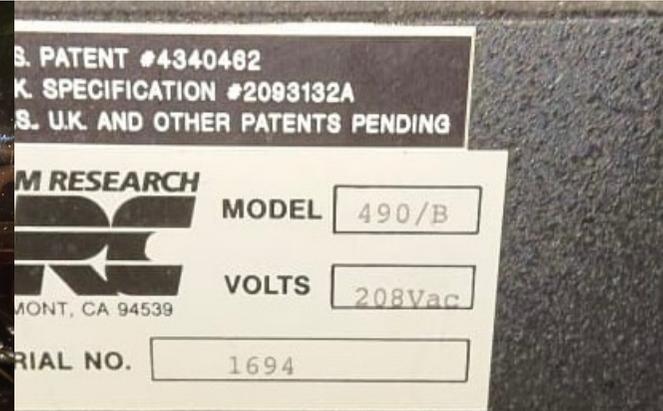
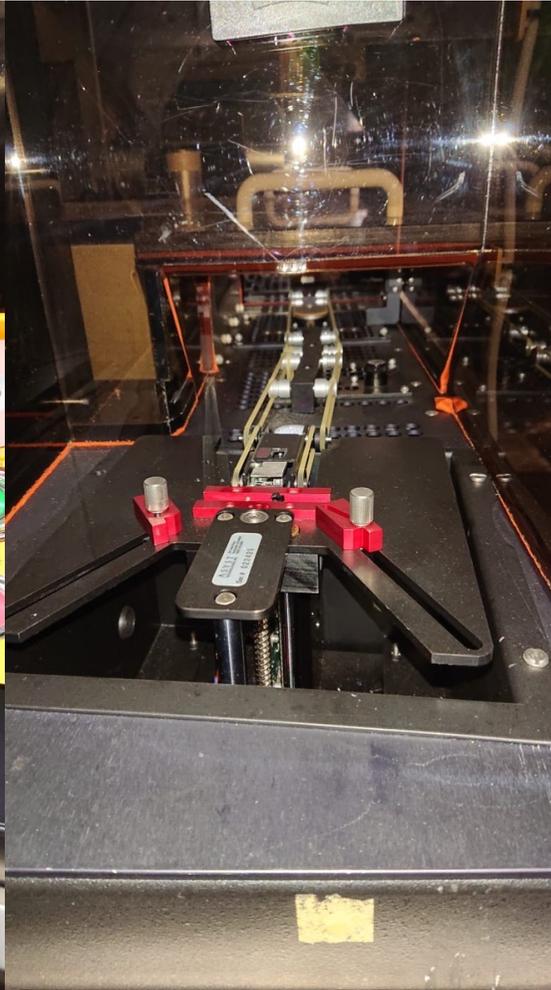
- Polysilicon: 490
- Wafer size: 6 inch
- Upgraded TFT monitors
- Wafer detection
- Incl maintenance console
- Conditon: AS IS (No Chiller, No pump but with ENI RF Generator)

Features:

- Single-wafer processing
- Fully automated microprocessor control
- Cassette-to-cassette wafer processing
- Vacuum load locked
- Programmable, variable electrode spacing
- Endpoint detection
- Configurable for 3-inch to 6-inch wafers
- Stand-alone or bulk-head mount configuration



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Solutions on Silicon BV

Your service partner for LAM Research Equipment

- **Equipment Support**
PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts
- **Process Support**
Process design, Improvement, Fab-to-Fab Transfer and Integration
- **Refurbishment**
From custom to complete refurbishment
- **Relocation**
Auditing, Fingerprinting, Decommissioning, Installation, Acceptance
- **Materials**
Supplier of first class second source materials

